## **Design of a 6-DoF Miniature Maglev Positioning Stage**

#### **for Application in Haptic Micromanipulation**



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**Master Thesis Defence 20th July 2011**

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#### **Outline**

- Introduction: Framework
- Requirements and Concept
- Sensors
- Actuators
- System Modelling
- Mechanical design
- Conclusion
- Demonstration
- Debate



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## **Introduction: Micromanipulation**

Miniaturisation of mechanical and electronic systems

Requires manipulation and assembly of micro parts (sizes of 1 mm and smaller)

Required precision too great for unaided human operator (often less than  $1 \mu m$ )

Varied and complex assembly tasks difficult for automatic systems







## **Introduction: Micromanipulation**



## **Introduction: The slave robot**

The positioner consists of two stages

• Coarse stage : stepper motor stages, 20 mm range

• Fine stage : Maglev stage, 200 µm range

The slave robot positions micro parts relative to a gripper

This thesis: Design of fine stage

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# **The fine stage**





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## **The fine stage: Considerations**

- Compact and simple design  $\rightarrow$  Affordable for small series assembly and prototyping
- Fragile parts  $\rightarrow$  Fine force resolution :
	- Low stiffness
	- Contact-free
	- Low moving mass
- User in the loop :
	- No absolute positioning
	- No accuracy requirement
	- Limited command bandwidth



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# **The fine stage: Specifications**

- Workspace : 200  $\mu$ m x 200  $\mu$ m x 200  $\mu$ m
- Rotation :  $\pm$  1°, three axes
- Velocities : 1 mm/s
- Moving mass : 8 g
- Part tolerances :  $1 \mu m 200 \ nm$  $\rightarrow$  Position resolution : 40 – 100 nm
- Fragile parts handling  $\rightarrow$  Force resolution : < 100 µN



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## **The fine stage: Maglev concept**





- 1. Base structure
- 2. Actuator coils
- 3. Sensor holders with sensors
- 4. Sensor targets
- 5. Floating disk
- 6. Actuator magnets





## **Sensors: Requirements and Principle**



Infrared Reflective Position Sensor

Linear "Near" range approx. 200 µm



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#### **Sensors: Problems**

Existing readout electronics not suitable for this application





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#### **Sensors: Results**

Fully redesigned readout electronics

Achieved range : 200 μm Noise :  $15 - 28$  nm peak-peak



Sensor range equal to motion range  $\rightarrow$  alignment needed

Drift



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## **Actuators: Principle and Requirements**



Peak force required:

- 40 mN vertical
- 20 mN horizontal

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#### **Actuators: Results**

- Actuator force
	- Vertical: 80 mN continuous, 160 mN peak
	- Horizontal : 10 mN continuous, 20 mN peak
- Parasitic forces/torques appear at off centered positions
- But manageable with simple control schemes
- Designed current amplifier board





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## **System modelling: Overview**

- Electro-mechanical model of fine stage
- Open-loop unstable  $\rightarrow$  Controller





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### **System modelling: Manufacturing tolerances**

- Randomised tolerances added to stage components in model
- Results: Position errors manageable as long as magnets and coils are aligned
- Alignment tool





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## **Mechanical design: Exploded view**

- 
- 2. Magnet and iron assembly
- 3. Adjustable sensor mount
- 4. Coils assembly
- 5. Horizontal and vertical position sensors
- 6. Coil alignment features
- 





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## **Mechanical design: Sensor adjustment**



#### Limited sensor range  $\rightarrow$  adjustable mounting



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## **Mechanical design: Final design**



- 1. Floating disk
- 2. Magnet and iron assembly
- 3. Adjustable sensor mount
- 4. Coils assembly
- 5. Horizontal and vertical position sensors



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## **Conclusion**

- Results
	- Designed and built 6-DoF maglev stage
	- Novel Lorentz actuator design
	- Low-noise optical position sensor
	- First closed-loop tests successful
- Recommendations
	- Further testing
	- Optimise actuator dimensions
	- Sensor with longer range
	- Design production prototype



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#### **Thank you for your attention!**





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## **Requirement comparison**



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### **State of the art: Micropositioning stages**





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#### **Existing 6-dof stage Kim et al.**





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# **Stage technology comparison**



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## **Stiff slave robot vs. force resolution**

• Slave robots: Positioning stages  $\rightarrow$  high stiffness "position actuators"

• Force sensitive tasks – fragile parts





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#### **Sensor readout electronics**



- Previously investigated by Rein Boshuisen and Ton de Boer
- Not optimized for this application:
	- 5V single supply
	- Range limited by saturation
- Improvements:
	- Redesign current source, amplifier
	- 15V symmetric supply
	- Low-noise components



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#### **Improved sensor readout**





## **Vertical coil characteristics**



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## **Horizontal coil characteristics**



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#### **Reluctance Actuators**



- Differential reluctance actuator
- 50 μN force range
- Target size 6 x 6 mm
- Designed, not tested



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#### **Current amplifiers**



Widlar bilateral current source

$$
I_{out} = -V_{in} \left(\frac{R_3}{R_1 R_5}\right)
$$
  

$$
R_1 = R_2
$$
  

$$
R_3 = R_4
$$

$$
R_1 + R_3 \gg R_5
$$



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#### **Simulation diagram**

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#### **Control Layout**







## **System modelling: Control loop**

• Closed loop BW: 100 Hz









#### **Frequency response: System and controller**





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#### **Frequency response: Sensitivity**





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#### **Floor vibrations (Mechatronics Lab)**





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### **Tolerances: All components**



#### **Tolerances: Selected components**

Technology



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### **CAD Design**



- 1. Base structure
- 2. Sensor alignment and support structure
- 3. Moving part
- 4. Actuator target
- 5. Actuator coil
- 6. Position sensor



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#### **Flexure mechanisms: FEM analysis**



Surface: von Mises stress (N/m^2) Surface Deformation: Displacement field



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### **Floating disk: Modal analysis**





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